

Index

A

absolute encoder, 66
acceptance angle, 21
active scan angle, 82
analytic raytracing, 4
angular resolution, 15
angular-scanning system, 1
angular transfer function (ATF),
13, 30
aperture shape factor, 15
astigmatism distortion, 145
axis-aligned rectangular bounding
box (AARBB), 35

B

barcode scanner, 1
base curve, 117
bilinear interpolation, 171
binary sequence, 68
blind zone, 233
boresight, 301

C

comb-drive, 220, 221
conic section, 33
conic-section scan pattern, 39
convergent beam scanning, 75

D

diffraction, 15
directional cosine, 45
director, 117
display screen, 174
doubly ruled surface, 119

drive functions of the mirrors
(DFOM), 2
dynamic focusing module (DFM),
167

E

electrostatic motor, 219
exclusion zone, 308

F

facet clear aperture, 79
field of regard (FOR), 301
flat field scanning lens, 360
flat-top beam, 16
flying spot scan, 1
focus shifter, 167
forward mapping, 170

G

G-C system, 145
G-G system, 145
Galvanometric scanner, 41
gimbaled mirror, 382
grazing incidence, 45

H

heliostat, 221

I

incremental encoder, 67
instantaneous scan center, 57
intersection of a ray and a flat
surface, 9
inverse mapping, 170

inverted pyramidal polygon scanner, 110

L

laser scanner resolution, 14
laser-beam-scanning system, 1
law of reflection, 2
law of refraction, 2
law of transmission, 2
lidar, 302
line of sight (LOS), 396
linear or curvilinear translation-scanning system, 1
locus, 57

M

magnetic encoder, 66
micro-opto-electro-mechanical systems (MOEMS), 219
micro-electro-mechanical systems (MEMS), 219
mirror drive function, 7
model scanner, 21
monogon scanner, 21

N

nano-electro-mechanical systems (NEMS), 227
narrow waist, 54

O

objective scanning, 359
oblique cone, 386
one-step method, 390
optical distortion, 213
optical doubling of the mechanical angle, 44
optical encoder, 65

P

P-G system, 145
plane mirror array, 30
pointing error, 338

pointing stability, 279
polygon, 75
polygon scanner, 360
position-finding error, 279
post-objective scanning, 360
prismatic polygon, 91
pseudorandom encoder, 69
pyramidal polygon, 110

Q

quadrant mirror array, 225
quadratic cone, 28
quartic cone, 28

R

ray direction vector, 5, 293
resolver, 66
resonant Galvanometric scanner, 42
right circular cone, 28, 43
Risley-prism-based beam-steering system, 4
ruled surface, 140
ruled surface directrix, 117
ruling, 66, 117

S

scan field, 2, 10
scan line bow, 165
scan pattern, 181, 182
scanning geometry, 239
shaft encoder, 65
single-facet scanner, 21
single-origin scanning, 39
singularity function, 308
slew rate, 305
Snell's law, 2, 252
software distortion correction, 168, 172

T

thick prism, 232
three-axis scanning system, 70

three-element Risley prism system,
398
tilted bearing, 329
total internal reflection (TIR), 235

V

vector scanning, 42

vignetting effect, 101

W

wedge prism, 232

X

XY scanning, 181



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